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Parameter	Value	Notes
Type of measure		Transmission reflection and scattering
Spectral range	400nm ÷ 900nm	Limited by the lamp spectrum and by the transmission of the optical components. The spectrometer could perform the measurements from 200nm to 1033nm.
Measurement time	$1s \div 10s$	Average integration time needed for the spectrometer measurements (depending on the coating properties).
Precision on relative measurements	≈ ±0.15%	Stability of the signal during the full measurement time by considering drift and noise from: -the spectrometer sensor; -the light source; -the background signals.
Size of the probe beam	Φ 4.5mm	Is the size of the light beam collected by the spectrometer aperture.

Value	Reference	Image/URL
0.97 kg/m ³	Polymer Data Handbook, Mark J., Oxford Univ. Press, New York (1999)	
360-870 KPa	Re-configurable Fluid Circuits by PDMS Elastomer Micromachining	http://mass.micro.uiuc.edu/ publications/papers/26.pdf
0.5	Polymer Data Handbook	
2.24 MPa	Polymer Data Handbook	
1.46 kJ/kg K	Polymer Data Handbook	
0.15 W/m K	Polymer Data Handbook	
2.3-2.8	Polymer Data Handbook	
1.4	Polymer Data Handbook	
$4x10^{13} \Omega m$	Polymer Data Handbook	
0.6x10 ⁶ cm ³ /g	Polymer Data Handbook	
N/A		
N/A		
	Value 0.97 kg/m³ 360-870 KPa 0.5 2.24 MPa 1.46 kJ/kg K 0.15 W/m K 2.3-2.8 1.4 4x10 ¹³ Ωm 0.6x10 ⁶ cm³/g N/A	Value Reference 0.97 kg/m³ Polymer Data Handbook, Mark J., Oxford Univ. Press, New York (1999) 360-870 KPa Re-configurable Fluid Circuits by PDMS Elastomer Micromachining 0.5 Polymer Data Handbook 2.24 MPa Polymer Data Handbook 1.46 kJ/kg K Polymer Data Handbook 2.3-2.8 Polymer Data Handbook 1.4 Polymer Data Handbook 4x10 ¹³ Ωm Polymer Data Handbook 0.6x10 ⁶ cm ³ /g Polymer Data Handbook N/A N/A

Property	Value	Reference	Image/URL
Wet etching method	tetrabutylammonium fluoride ($C_{16}H_{36}FN$) + n-methyl-2- pyrrolidinone (C_5H_9NO) 3:1	J. Garra, T. Long, J. Currie, T. Schneider, R. White, M. Paranjape, "Dry Etching of Polydimethylsiloxane for Microfluidic Systems", Journal of	http://scitation.aip.org/jou nals/doc/JVTAD6- ft/vol_20/iss_3/975_1.htm
Plasma etching method	CF ₄ +O ₂	J. Garra, T. Long, J. Currie, T. Schneider, R. White, M. Paranjape, "Dry Etching of Polydimethylsiloxane for Microfluidic Systems", Journal of Vacuum Science and Technology, A20, pp 975-982, 2002.	http://scitation.aip.org/jou nals/doc/JVTAD6- ft/vol_20/iss_3/975_1.htm
Adhesion to silicon dioxide	Excellent	Re-configurable Fluid Circuits by PDMS Elastomer Micromachining	http://mass.micro.uiuc.edu publications/papers/26.pd
Biocompatibility	Noniritating to skin, no adverse effect on rabbits and mice, only mild inflammatory reaction when implanted	Polymer Data Handbook; Belanger MC, Marois Y. Hemocompatibility, biocompatibility, inflammatory and in vivo studies of primary reference materials low-density polyethylene and polydimethylsiloxane: a review. J Biomed Mater Res 2001;58(5):467–77.	
Hydrophobicity	Highly hydrophobic, contact angle 90-120°	Re-configurable Fluid Circuits by PDMS Elastomer Micromachining	http://mass.micro.uiuc.edu publications/papers/26.pd
Melting Point	-49.9–40°	Knovel Critical Tables	

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